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02/14/02

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPLICATION		FILING DATE		CLASS	SUBCLASS	GAU	EXAMINER				
APPL NUM	10077072	FILING DATE	02/14/2002	CLASS	315	SUBCLASS	111.21	GAU	2817	EXAMINER	lll
**APPLICANTS: Fischer Andreas; Trussell Dave; Kennedy Bill; Loewenhardt Peter;											
**CONTINUING DATA VERIFIED: None <i>lll</i>											
** FOREIGN APPLICATIONS VERIFIED: None <i>lll</i>											
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/> RESCIND <input type="checkbox"/>											
Foreign priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no											
35 USC 119 conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no											
Verified and Acknowledged Examiners's initials <i>lll</i>											
ATTORNEY DOCKET NO P0877											
TITLE : Plasma processing apparatus and method for confining an RF plasma under very high gas flow and RF power Density conditions											
U.S. DEPT. OF COMM./PAT. & TM.-PTO-435L (Rev. 12-94)											

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
Assistant Examiner		Total Claims	Print Claim for O.G.
Primary Examiner		DRAWING	
PREPARED FOR ISSUE		Sheets Drwg.	Figs. Drwg.
Application Examiner		Print Fig.	
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